

## **DC Field Emission Scanning Measurements** on Electropolished Niobium

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Enhanced field emission (EFE) from surface irregularities and particulates is one major obstacle for high gradient operations of SC Nb cavities.

 $E_{peak} \approx E_{p(iris)} = 2.E_{acc}$ 

**Strategy for improvement:** 

- **Avoid field emission by improved surface cleaning** e.g. Electropolishing (EP), High pressure rinsing (HPR), Dry ice cleaning (DIC)
- FE measurements on Nb samples cleaned inside Nb cavities Automation of FESM with LabVIEW for faster scans, SEM images

## **Regulated V- scans**

Nb sample EP at Saclay (Nb thickness removed 140 µm)

• 1st series:  $\Phi$ Anode = 300  $\mu$ m,  $\Delta z$ = 50  $\mu$ m (± 5  $\mu$ m), scan area (A) = 12mm×12mm

## **DC Field Emission Scanning Microscope (FESM)**





• 1st series:  $\Phi$ Anode = 300  $\mu$ m,  $\Delta z$ = 50  $\mu$ m (± 5  $\mu$ m), scan area (A) = 12mm×12mm



2nd series: ΦAnode = 100 μm, Δz= 40 μm (± 5 μm), A = 7.5 mm × 7.5 mm



Conclusions

**Regulated V- scans on ~ cm<sup>2</sup> sample area EP** only up to 30 emitters / cm<sup>2</sup> at 120 MV/ m EP + HPR No FE at 40 MV / m ( $\equiv E_{acc} \approx 20$  MV / m) Reduced field emission up to 14 emitters / cm<sup>2</sup> at 120 MV/ m ~3 emitters might be fixed due to FE current during scans before HPR. High resolution scans and local measurements ( $\Phi_{anode} = 2 \mu m$ ) (EP + HPR)(EP only) E<sub>on</sub> (1 nA) 33 MV/ m to 46 MV/ m 48 MV/ m to 77 MV/m  $\beta$  value 31 to 231 18 to 167 10<sup>-13</sup> to 10<sup>-20</sup> m<sup>2</sup> 10<sup>-13</sup> to 10<sup>-19</sup> m<sup>2</sup> S-parameter The SEM images show emitter as a flake like object or a particle. **Acknowledgement:** 

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